

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/6303	Serial No. 09/965,370
SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Chung, et al.	Confirmation No. Unknown
(Use several sheets if necessary)		Filing Date 09/26/2001	Group Unknown
Examiner Unknown			

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*Examiner Initial	Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
EF	A1	2001/0042799	11/22/2001	Kim, et al.	239	553	02/02/2001
	A2						
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Foreign Patent Documents

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OTHER ART

*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.
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	C2

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11/14/03

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. AMAT/6303	Serial No. 09/965,370
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Applicant Chung, et al.	Confirmation No.: 6507
(Use several sheets if necessary)		Filing Date 09/26/2001	Group 1762
Examiner Unknown			

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*Examiner Initial	Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
EF	A1	5,529,955	Hibino, et al.	437	195	08/25/1994
	A2					
	A3					
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	A12					
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Foreign Patent Documents

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OTHER ART

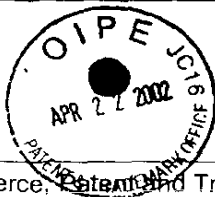
*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.
EF	C1 R.C. Ellwanger, "An Integrated Aluminum/CVD-W Metallization Process For Sub-Micron Contact Filling", June 11-12, 1991 IEEE Catalog No. 91 TH0359-0, pages 41-50.
EF	C2 Kaanta, et al. "Dual Damascene: A ULSI Wiring Technology" June 11-12, 1991 VMIC

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



Sheet 1 of 11 sheet(s)

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		Chung, et al.	Unknown
(Use several sheets if necessary)		Filing Date	Group
Examiner Unknown		September 26, 2001	Unknown

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CF	A1	4,813,846	03/21/89	Helms	414	744.1	04/29/87
	A2	4,917,556	04/17/90	Stark et al.	414	217	05/26/89
	A3	4,951,601	08/28/90	Maydan, et al.	118	719	06/23/89
	A4	5,000,113	03/19/91	Wang et al.	118	723	12/19/86
	A5	5,186,718	02/16/93	Tepman et al.	29	25.01	04/15/91
	A6	5,205,077	04/27/93	Wittstock	51	165 R	08/28/91
	A7	5,234,561	08/10/93	Randhawa et al.	204	192.38	08/25/88
	A8	5,259,881	11/09/93	Edwards, et al.	118	719	05/17/91
	A9	5,286,296	02/15/94	Sato et al.	118	719	01/09/92
	A10	5,609,689	03/11/97	Kato et al.	118	719	06/03/96
	A11	5,667,592	09/16/97	Boitnott et al.	118	719	04/16/96
	A12	5,674,786	10/07/97	Turner et al.	437	225	06/05/95
	A13	5,695,564	12/09/97	Imahashi	118	719	08/03/95
	A14	5,730,801	03/24/98	Tepman et al.	118	719	08/23/94
	A15	5,788,447	08/04/98	Yonemitsu et al.	414	217	08/05/96
	A16	5,788,799	08/04/98	Steger, et al.	156	345	06/11/96
	A17	5,801,634	09/01/98	Young et al.	340	635	09/08/97
	A18	5,856,219	01/05/99	Naito et al.	438	241	08/18/97
	A19	5,866,213	02/02/99	Foster et al.	427	573	07/19/97
	A20	5,866,795	02/02/99	Wang et al.	73	1.36	03/17/97
	A21	5,882,165	03/16/99	Maydan et al.	414	217	09/10/97

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EF	A1	6,268,291	07-31-2001	Andricacos et al.	438	694	12-03-1998
	A2	6,249,055	06-19-2001	Dubin	257	758	02-03-1998
	A3	6,160,315	12-12-2000	Chiang et al.	257	762	01-06-2000
	A4	6,066,892	05-23-2000	Ding et al.	257	751	05-14-1998
	A5	6,037,257	03-14-2000	Chiang et al.	438	687	05-08-1997
	A6	5,744,394	04-28-1998	Iguchi et al.	438	276	04-23-1997
EF	A7	5,654,232	08-05-1997	Gardner	438	661	03-15-1996
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*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.
EF	C1 USSN 09/518,004. Filed March 2, 2000

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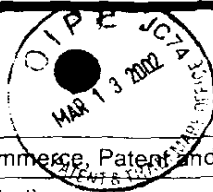
U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					MAR 01 2002 Docket No. AMAT/6303/CPI/ COPPER/PJS		Serial No. 09/965,370	
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EF	A118	2001/0011526	08/09/2001	Doering, et al.	118	729	01/16/2001	
	A119	2001/0031562	10/18/2001	Raaijmakers, et al.	438	770	02/22/2001	
	A120	2001/0034123	10/25/2001	Jeon, et al.	438	643	04/06/2001	
	A121							
	A122							
EF	A123							
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*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation YES NO	
EF	B34	2001-62244	03/13/2001	JP	B01D	53/34		X
	B35	198 20 147	07/01/1999	DE	H01L	21/3205		X
	B36	196 27 017	01/09/1997	DE	H01L	21/283		X
	B37	2 626 110	07/21/1989	FR	H01L	39/24		X
	B38	2 692 597	12/24/1993	FR	C23C	16/00		X
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*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
EF	C18	Min, et al., "Chemical Vapor Deposition of Ti-Si-N Films with Alternating Source Supply", <i>Mat. Res. Soc. Symp. Proc.</i> , Vol. 564 (Apr. 5, 1999), pp. 207-210						
	C19	Bedair, "Atomic layer epitaxy deposition processes", <i>J. Vac. Sci. Technol.</i> 12(1) (Jan/Feb 1994)						
	C20	Yamaga, et al., "Atomic layer epitaxy of ZnS by a new gas supplying system in a low-pressure metalorganic vapor phase epitaxy", <i>J. of Crystal Growth</i> 117 (1992), pp. 152-155						
EF	C21	Elam, et al., "Nucleation and growth during tungsten atomic layer deposition on SiO ₂ surfaces," <i>Thin Solid Films</i> 386 (2001) Pages 41 - 52, (Accepted Dec. 14, 2000).						

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EF	A55	5,458,084	10/17/95	Thorne et al.	117	89	12/09/1993
	A56	5,469,806	11/28/95	Mochizuki et al.	117	97	08/20/1993
	A57	5,480,818	01/02/96	Matsumoto et al.	437	40	02/09/1993
	A58	5,483,919	01/16/96	Yokoyama et al.	117	89	08/17/1994
	A59	5,484,664	01/16/96	Kitahara et al.	428	641	01/21/1994
	A60	5,503,875	04/02/96	Imai et al.	427	255.3	03/17/1994
	A61	5,521,126	05/28/96	Okamura et al.	437	235	06/22/1994
	A62	5,527,733	06/18/96	Nishizawa et al.	437	160	02/18/1994
	A63	5,532,511	07/02/96	Nishizawa et al.	257	627	03/23/1995
	A64	5,540,783	07/30/96	Eres et al.	118	725	05/26/1994
	A65	5,601,651	02/11/97	Watabe	118	715	12/14/1994
	A66	5,616,181	04/01/97	Yamamoto et al.	118	723 ER	11/21/1995
EF	A67	5,637,530	06/10/97	Gaines et al.	114	105	06/10/1996

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							YES	NO
EF	B17	99/41423 A2	08/19/1999	WO	C23C	---		X
EF	B18	99/29924 A1	06/17/1999	WO	C23C	16/04		X
EF	B19	96/18756 A1	06/20/1996	WO	C23C	16/08		X

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EF	C8	Ritala, et al., "Perfectly conformal TiN and Al ₂ O ₃ films deposited by atomic layer deposition", <i>Chemical Vapor Deposition</i> , Vol. 5(1) (January 1999), pp. 7-9.
EF	C9	Klaus, et al., "Atomically controlled growth of tungsten and tungsten nitride using sequential surface reactions" <i>Appl. Surf. Sci.</i> Vol. 162-163 (2000) pp. 179-191.

EXAMINER: [Signature] Date: 1/14/03
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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
EF	A106	6,200,893	03/13/2001	Sneh	438	685	03/11/1998
	A107	6,203,613	03/20/2001	Gates, et al.	117	104	10/19/1999
	A108	6,207,302	03/27/2001	Sugiura, et al.	428	690	03/02/1998
	A109	6,248,605	06/19/2001	Harkonen, et al.	438	29	06/02/1999
	A110	6,270,572	08/07/2001	Kim, et al.	117	93	08/09/1999
	A111	6,287,965	09/11/2001	Kang, et al.	438	648	02/23/2000
	A112	6,291,876	09/18/2001	Stumborg, et al.	257	632	08/20/1998
	A113	6,305,314	10/23/2001	Sneh, et al.	118	723 R	12/17/1999
	A114	6,306,216	10/23/2001	Kim, et al.	118	725	07/12/2000
	A115	6,316,098	11/13/2001	Yitzchaik, et al.	428	339	03/23/1999
	A116	2001/0000866	05/10/2001	Sneh, et al.	118	723 R	11/29/2000
EF	A117	2001/0009140	07/26/2001	Bondestam, et al.	118	725	01/25/2001

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EF	B30	04-031396 A	02/03/1992	JP	C30B	25/14		X
	B31	06-291048	10/18/1994	JP	H01L	21/205		X
	B32	08-264530	10/11/1996	JP	H01L	21/3205		X
EF	B33	11-269652	10/05/1999	JP	C23C	16/44		X

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EF	C16	Lee, "The Preparation of Titanium-Based Thin Film by CVD Using Titanium Chlorides as Precursors", <i>Chemical Vapor Deposition</i> , 5(2) (Mar. 1999), pp. 69-73.
EF	C17	Martensson, et al., "Atomic Layer Epitaxy of Copper, Growth & Selectivity in the Cu (II)-2,2,6,6-Tetramethyl-3, 5-Heptanedion ATE/H ₂ Process", <i>J. Electrochem. Soc.</i> 145(8) (Aug. 1998) pp

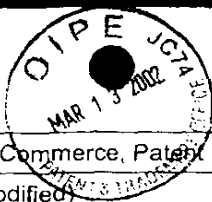
EXAMINER Initial: [Signature] Considered: [Signature] in conformance with MPEP 609.01(a) through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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U.S. Patent Documents								
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EF	A94	6,001,669	12/14/99	Gaines et al.	438	102	07/21/1992	
	A95	6,015,590	01/18/00	Suntola et al.	427	255.23	11/28/1995	
	A96	6,025,627	02/15/00	Forbes et al.	257	321	05/29/1998	
	A97	6,036,773	03/14/00	Wang et al.	117	97	03/27/1997	
	A98	6,042,652	03/28/00	Hyun et al.	118	719	09/07/1999	
	A99	6,043,177	03/28/00	Falconer et al.	502	4	01/21/1997	
	A100	6,124,158	09/26/00	Dautartas et al.	438	216	06/08/1999	
	A101	6,113,977	09/05/00	Soininen et al.	427	64	09/11/1997	
	A102	6,130,147	10/10/00	Major et al.	438	604	03/18/1997	
	A103	6,139,700	10/31/00	Kang et al.	204	192.17	09/30/1998	
	A104	6,174,377	01/16/2001	Doering, et al.	118	729	01/04/1999	
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							YES	NO
EF	B27	60-065712 A	04/15/1985	JP	C01B	33/113		X
EF	B28	03-048421	03/01/1991	JP	H01L	21/302		X
EF	B29	03-286531	12/17/1991	JP	H01L	21/316		X
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*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
EF	C13	Martensson, et al., "Atomic Layer Epitaxy of Copper on Tantalum", <i>Chemical Vapor Deposition</i> , 3(1) (Feb. 1, 1997), pp. 45-50.						
EF	C14	Ritala, et al. "Atomic Layer Epitaxy Growth of TiN Thin Films", <i>J. Electrochem. Soc.</i> , 142(8) (Aug. 1995), pp. 2731-737.						
EF	C15	Elers, et al. "NbC15 as a precursor in atomic layer epitaxy" <i>Appl. Surf. Sci.</i> Vol. 82/83 (1994) pp.						

EXAMINER: [Signature] 11/18/03
 I have reviewed the reference(s) cited in this communication and find that the same is/are in conformance with 35 U.S.C. 102(b). Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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	A69	5,644,128	07/01/97	Wollnik et al.	250	251	08/25/1994
	A70	5,693,139	12/02/97	Nishizawa et al.	117	89	06/15/1993
	A71	5,705,224	01/06/98	Murota et al.	427	248.1	01/31/1995
	A72	5,707,880	01/13/98	Aftergut et al.	437	3	01/17/1997
	A73	5,711,811	01/27/98	Suntola et al.	118	711	11/28/1995
	A74	5,730,802	03/24/98	Ishizumi et al.	118	719	12/27/1996
	A75	5,747,113	05/05/98	Tsai	427	255.5	07/29/1996
	A76	5,749,974	05/12/98	Habuka et al.	118	725	07/13/1995
	A77	5,796,116	08/18/98	Nakata et al.	257	66	07/25/1995
	A78	5,807,792	09/15/98	Ilg et al.	438	758	12/18/1996
	A79	5,830,270	11/03/98	McKee et al.	117	106	08/05/1996
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	B21	93/02111 A1	02/04/1993	WO	C08F	4/78		X
	B22	91/10510 A1	07/25/1991	WO	B01J	37/02		X
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EF	C10	Min, et al., "Atomic layer deposition of TiN thin films by sequential introduction of Ti precursor and NH/sub3/", <i>Symp.: Advanced Interconnects and Contact Materials and Processes for Future Integrated Circuits</i> (Apr. 12-16, 1998), pp. 227-232

Examiner's reference to other art is not intended to be a citation of prior art under 35 U.S.C. 102 or 103, and is not to be considered as such. Information is provided for the applicant's information through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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	A46	5,348,911	09/20/94	Jurgensen et al.	117	91	04/26/1993
	A47	5,374,570	12/20/94	Nasu et al.	437	40	08/19/1993
	A48	5,395,791	03/07/95	Cheng et al.	437	105	10/20/1993
	A49	5,438,952	08/08/1995	Otsuka	117	84	01/31/1994
	A50	5,439,876	08/08/95	Graf et al.	505	447	08/16/1993
	A51	5,441,703	08/15/95	Jurgensen	422	129	03/29/1994
	A52	5,443,033	08/22/95	Nishizawa et al.	117	86	03/11/1994
	A53	5,443,647	08/22/95	Aucoin et al.	118	723 ME	07/11/1994
EF	A54	5,455,072	10/03/95	Bension et al.	427	255.7	11/18/1992

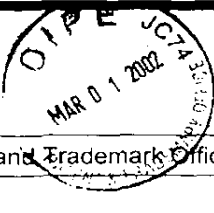
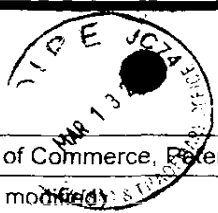
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EF	B13	00/54320 A1	09/14/2000	WO	H01L	21/44		X
	B14	00/16377 A2	03/23/2000	WO	H01L	---		X
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EF	C7	Niinisto, et al., "Synthesis of oxide thin films and overlayers by atomic layer epitaxy for advanced applications". <i>Mat. Sci. & Eng.</i> , Vol. B41 (1996). pp. 23-29.

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EF	A28	5,225,366	Yoder	437	108	06/22/1990
	A29	5,246,536	Nishizawa et al.	156	610	03/10/1989
	A30	5,250,148	Nishizawa et al.	156	611	11/12/1991
	A31	5,254,207	Nishizawa et al.	156	601	11/30/1992
	A32	5,256,244	Ackerman	156	613	02/10/1992
	A33	5,270,247	Sakuma et al.	437	133	07/08/1992
	A34	5,278,435	Van Hove et al.	257	184	06/08/1992
	A35	5,281,274	Yoder	118	697	02/04/1993
	A36	5,290,748	Knuuttila et al.	502	228	07/16/1992
	A37	5,294,286	Nishizawa et al.	156	610	01/12/1993
	A38	5,296,403	Nishizawa et al.	437	133	10/23/1992
	A39	5,300,186	Kitahara et al.	156	613	04/07/1992
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EF	C5 George, et al., "Atomic layer controlled deposition of SiO ₂ and Al ₂ O ₃ using ABAB... binary reaction sequence chemistry", <i>Appl. Surf. Sci.</i> , Vol. 82/83 (1994), pp. 460-467.
EF	C6 Wise, et al., "Diethyldiethoxysilane as a new precursor for SiO ₂ growth on silicon", <i>Mat. Res. Soc. Symp. Proc.</i> , Vol. 224 (1994), pp. 27-32.

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EF	A14	4,859,627	08/22/89	Sunakawa	437	81	07/01/1988	
	A15	4,861,417	08/29/89	Mochizuki et al.	156	610	03/24/1988	
	A16	4,876,218	10/24/89	Pessa et al.	437	107	09/26/1988	
	A17	4,927,670	05/22/1990	Erbil	427	255.3	06/22/1988	
	A18	4,931,132	06/05/90	Aspnes et al.	156	601	10/07/1988	
	A19	4,960,720	10/02/90	Shimbo	437	105	08/24/1987	
	A20	4,975,252	12/04/90	Nishizawa et al.	422	245	05/26/1989	
	A21	4,993,357	02/19/91	Scholz	118	715	12/21/1989	
	A22	5,013,683	05/07/91	Petroff et al.	437	110	01/23/1989	
	A23	5,082,798	01/21/92	Arimoto	437	108	09/27/1990	
	A24	5,085,885	02/04/92	Foley et al.	477	38	09/10/1990	
	A25	5,091,320	02/25/92	Aspnes et al.	437	8	06/15/1990	
	A26	5,130,269	07/14/92	Kitahara et al.	437	111	04/25/1989	
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EF	C3	Yamauchi, et al. "Atomic-layer chemical-vapor-deposition of silicon dioxide films with extremely low hydrogen						

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	A2	4,389,973	06/28/83	Suntola et al.	118	725	12/11/1981
	A3	4,413,022	11/01/83	Suntola et al.	427	255.2	06/21/1979
	A4	4,486,487	12/04/84	Skarp	428	216	04/25/1983
	A5	4,767,494	08/30/88	Kobayashi et al.	156	606	09/19/1986
	A6	4,806,321	02/21/89	Nishizawa et al.	422	245	07/21/1985
	A7	4,829,022	05/09/89	Kobayashi et al.	437	107	12/09/1986
	A8	4,834,831	05/30/89	Nishizawa et al.	156	611	09/04/1987
	A9	4,838,983	06/13/89	Schumaker et al.	156	613	03/18/1988
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	A11	4,840,921	06/20/89	Matsumoto	437	89	06/30/1988
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	B3	01/36702 A1	05/25/2001	WO	C23C	16/00		X
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EF	C1	Hultman, et al., "Review of the thermal and mechanical stability of TiN-based thin films", <i>Zeitschrift Fur Metallkunde</i> , 90(10) (Oct. 1999), pp. 803-813

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EF	C1	Ohba, et al., "Thermal Decomposition of Methylhydrazine and Deposition Properties of CVD TiN Thin Films", Conference Proceedings, Advanced Metallization for ULSI Applications in 1993 (1994), pp. 143-149	
	C2	Scheper, et al., "Low-temperature deposition of titanium nitride films from dialkylhydrazine-based precursors", Materials Science in Semiconductor Processing 2 (1999), pp. 149-157	
	C3	Suzuki, et al., "A 0.2- μ m contact filling by 450°C-hydrazine-reduced TiN film with low resistivity", IEDM 92-979, pp. 11.8.1 - 11.8.3	
	C4	Suzuki, et al., "LPCVD-TiN Using Hydrazine and TiCl ₄ ", VMIC Conference (June 8-9, 1993), pp. 418-423	
	C5	IBM Tech. Disc. Bull. "Knowledge-Based Dynamic Scheduler in Distributed Computer Control, (June 1990), pp. 80-84	
	C6	IBM Tech. Disc. Bull. "Multiprocessor and Multitasking Architecture for Tool Control of the Advanced via Inspection Tools" (May 1992), pp. 190-191	
	C7	McGeachin, S., "Synthesis and properties of some β -diketimines derived from acetylacetone, and their metal complexes", Canadian J. of Chemistry, Vol. 46 (1968), pp.1903-1912	
	C8	Solanki, et al., "Atomic Layer deposition of Copper Seed Layers", Electrochemical and Solid State Letters, 3(10) (2000), pp. 479-480	
	C9	NERAC.COM Retro Search: Atomic Layer Deposition of Copper, dated October 11, 2001	
	C10	NERAC.COM Retro Search: Atomic Layer Deposition / Epitaxy Aluminum Oxide Plasma, dated October 2, 2001	
	C11	NERAC Search abstract of "Atomic Layer deposition of Ta and Ti for Interconnect Diffusion Barriers", by Rossnagel, et al., J. Vac. Sci. & Tech., 18(4) (July 2000)	
	C12	Abstracts of articles re atomic layer deposition	
	C13	Abstracts of search results re atomic layer deposition, search dated January 24, 2002	

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Examiner	B72	04-031391	02/03/1992	JP	C30B	23/08	<input type="checkbox"/>	<input type="checkbox"/>
					Date Considered	1/18/03		

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SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Chung, et al.	Confirmation No.: Unknown
(Use several sheets if necessary)		Filing Date September 26, 2001	Group Unknown
Examiner Unknown			

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
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EF	B25	64-082676	03/28/1989	JP	H01L	29/80	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B26	64-090524	04/07/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B27	01-103982	04/21/1989	JP	C30B	23/08	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B28	01-103996	04/21/1989	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
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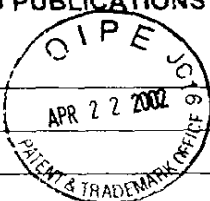
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Examiner	B48	02-074029	03/14/1990	JP	H01L	21/205	<input type="checkbox"/>	<input type="checkbox"/>
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Examiner					Date Considered 11/18/03

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